

IAP5 Rec'd PCT/PTO 27 SEP 2006

PATENT
8007-1118
10/594567

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of

Masaru HOSOKAWA et al. Conf.

Application No. NEW NATIONAL PHASE Group

Filed September 27, 2006 Examiner

MATERIAL FOR CHEMICAL VAPOR DEPOSITION AND THIN FILM FORMING
METHOD

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

September 27, 2006

Sir:

The following preliminary amendments and remarks are respectfully submitted in connection with the above-identified application.

Amendments to the Claims are reflected in the listing of claims which begin on page 2 of this paper.

Remarks begin on page 5 of this paper.